

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Chen, et al.	Conf. No.: 1057
Serial No.: 10/604,058	Art. Unit: 1763
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Title: PLASMA PROCESSING MATERIAL RECLAMATION AND REUSE	Docket. No.: FIS920030132US1 (IBMF-0018)

AF Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AFTER-FINAL AMENDMENT

Sir:

I. INTRODUCTORY COMMENTS

This paper is in response to the Final Office Action of 21 May 2007. Please amend the above-referenced patent application as follows:

The Amendments to the Claims are reflected in the listing of the claims that begins on page 2 of this paper.

Remarks begin on page 5 of this paper.